

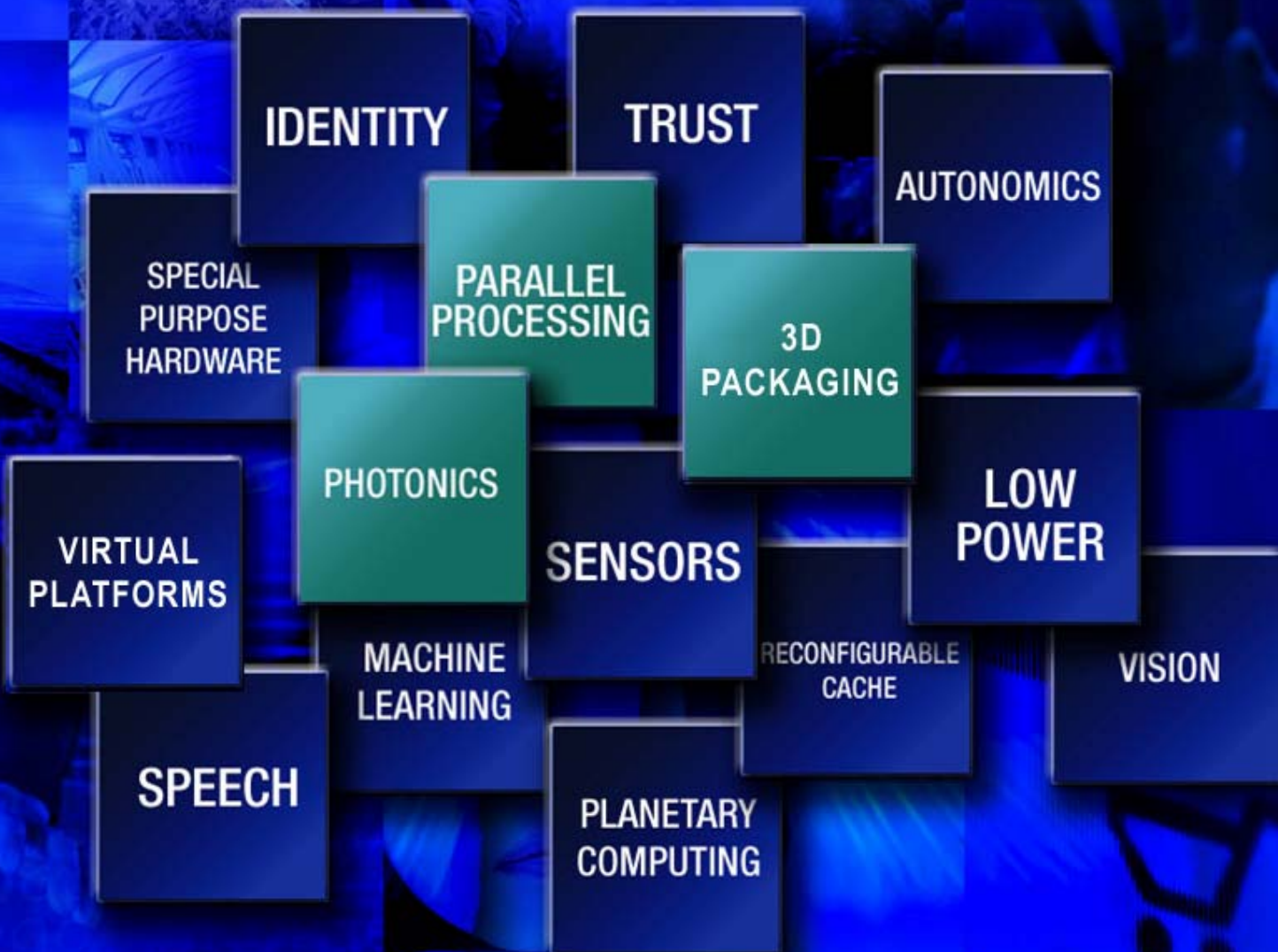
# 3D circuits & their test challenges

**TM Mak**

**GSRC Technical Liaison  
Test Technology**

What is new in computing?

# *Next Decade's Platform Evolution*





# *Trend to Many-Core*

Many-Core



Multi-Core



Dual-Core



Hyper-threading



Multi Processor



Can you program it?

Can we feed it?

# *Domain-Specific Parallel Programming*

Parallel Source

Parallel Compiler

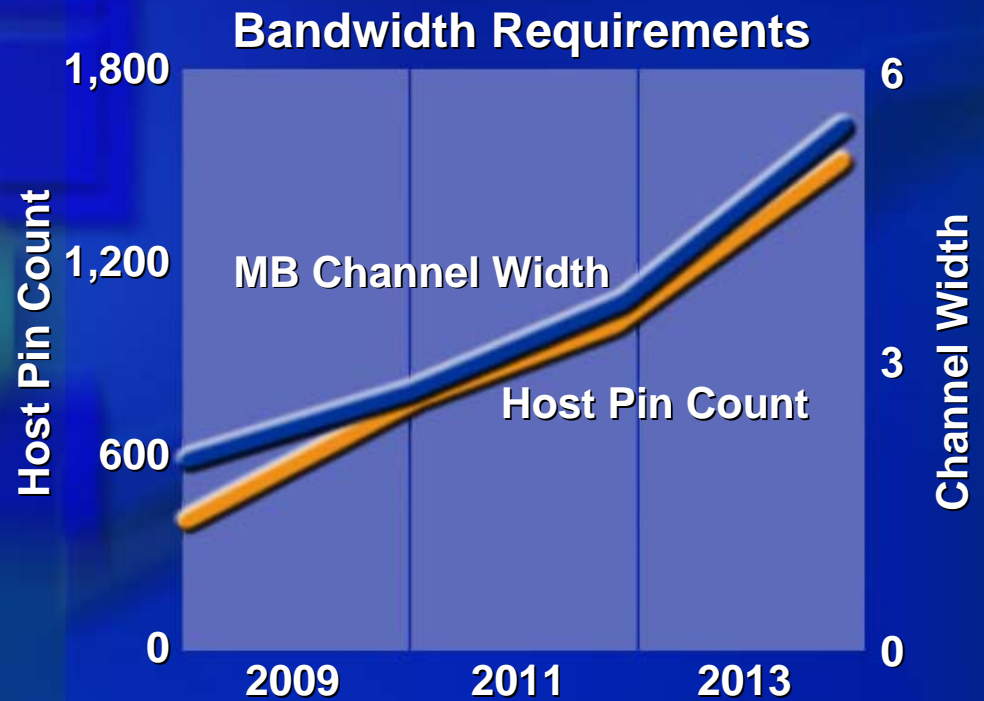
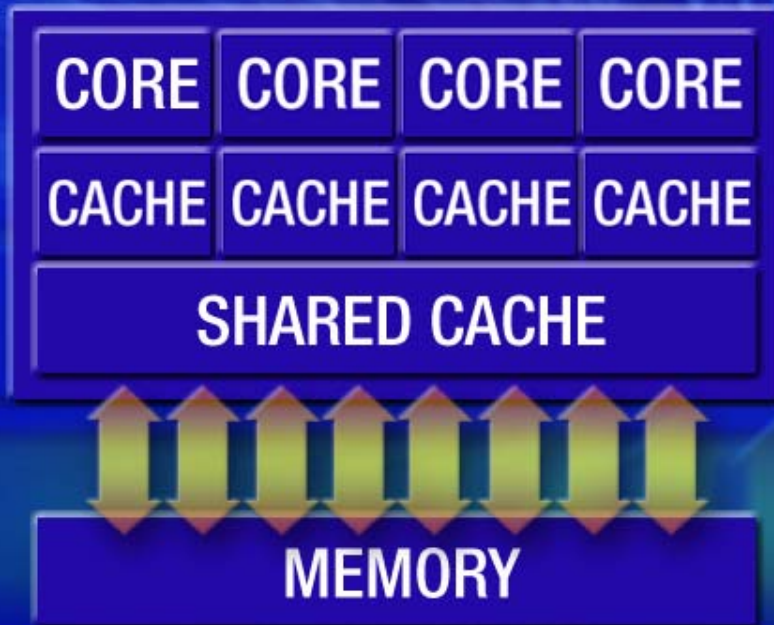
Thread Thread Thread Thread

Many-Core  
Run Time

Can you program it?

Can we feed it?

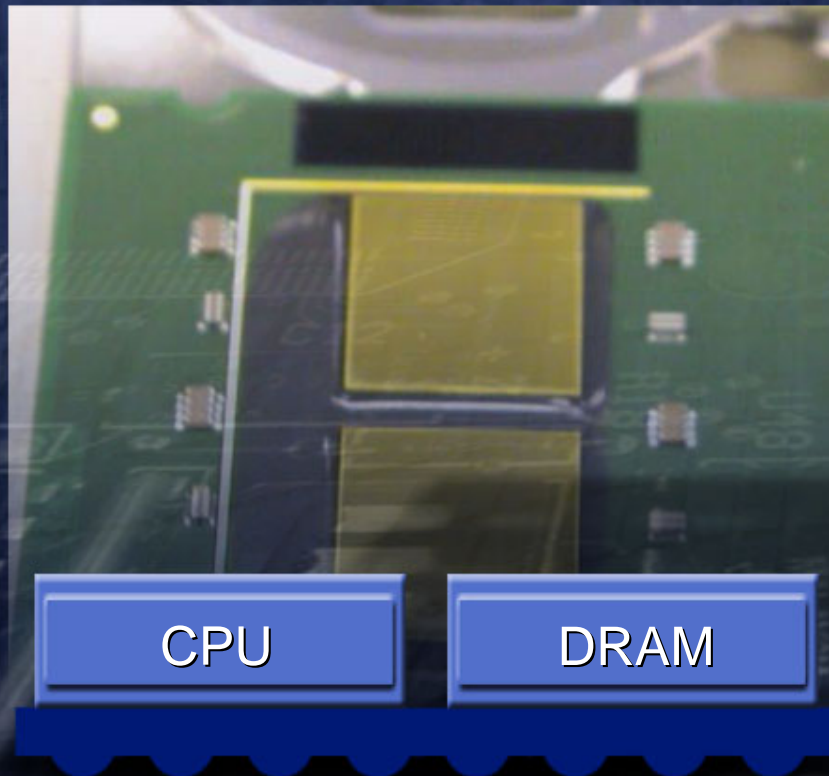
# Memory Bandwidth Challenge



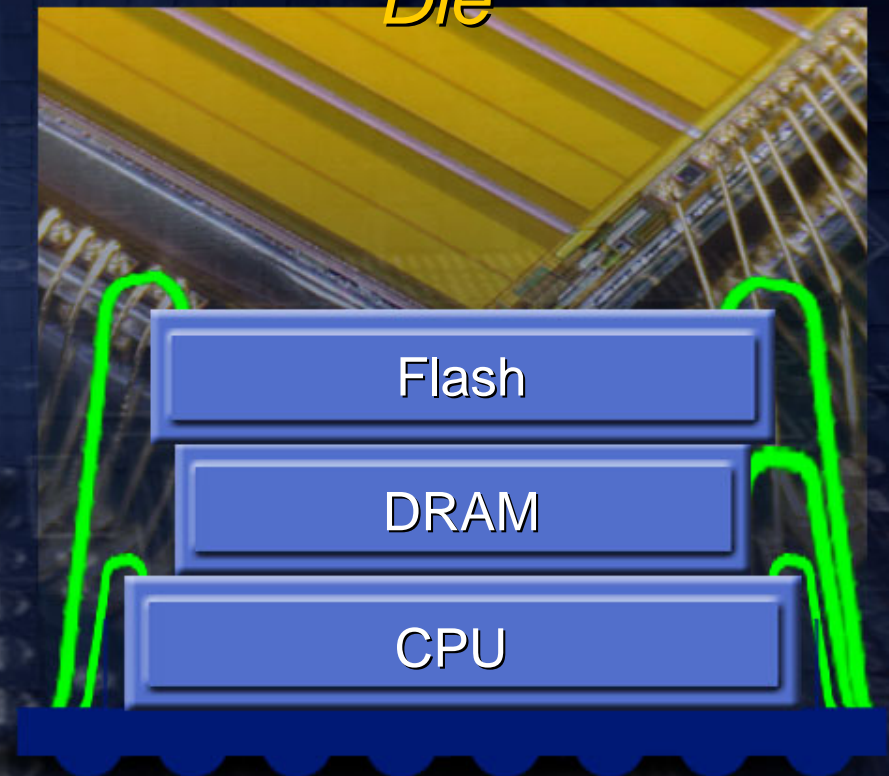


# Today's Packaging Technology

## Multi-Chip Package

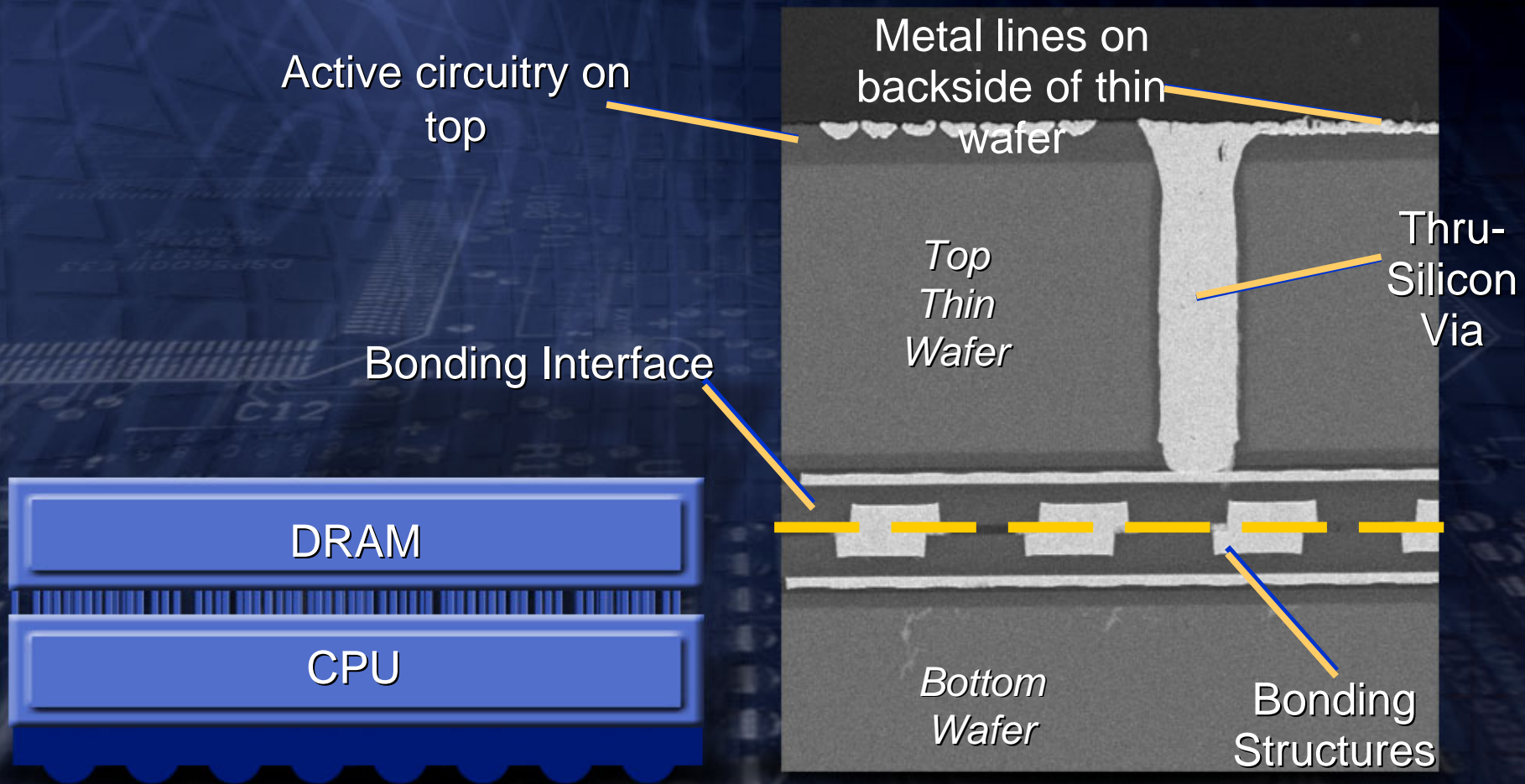


## Wire-Bonded Stacked Die



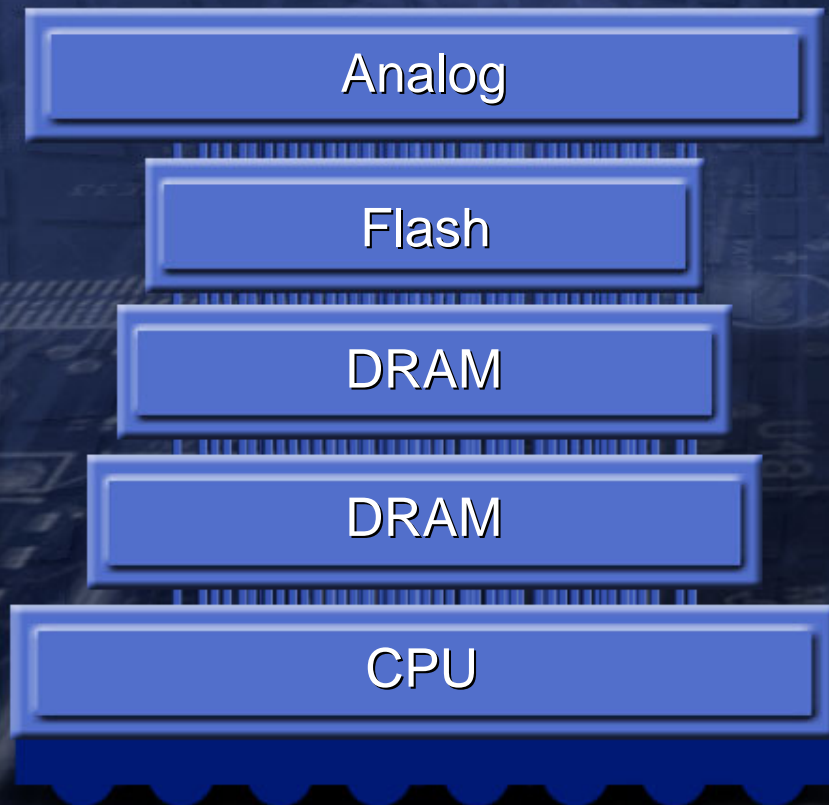
# 3D Stacking Research

## *Wafer Stacking*



# 3D Stacking Research

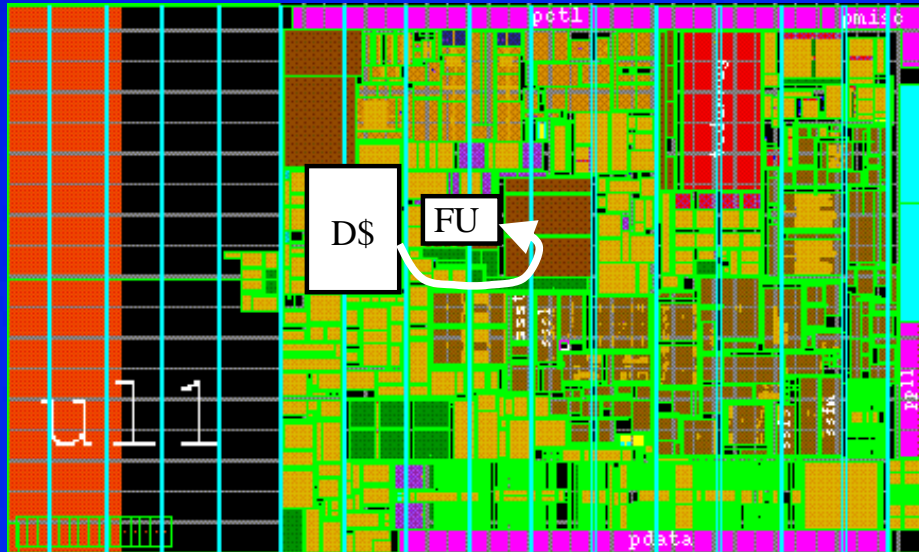
## *Die Stacking*



Source: Intel



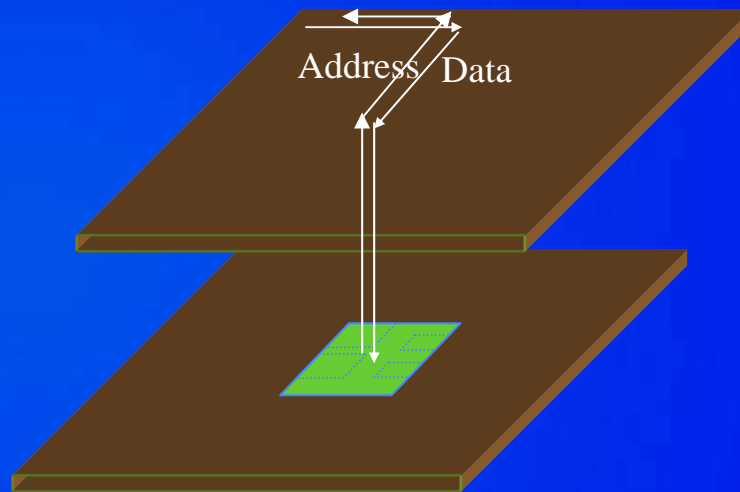
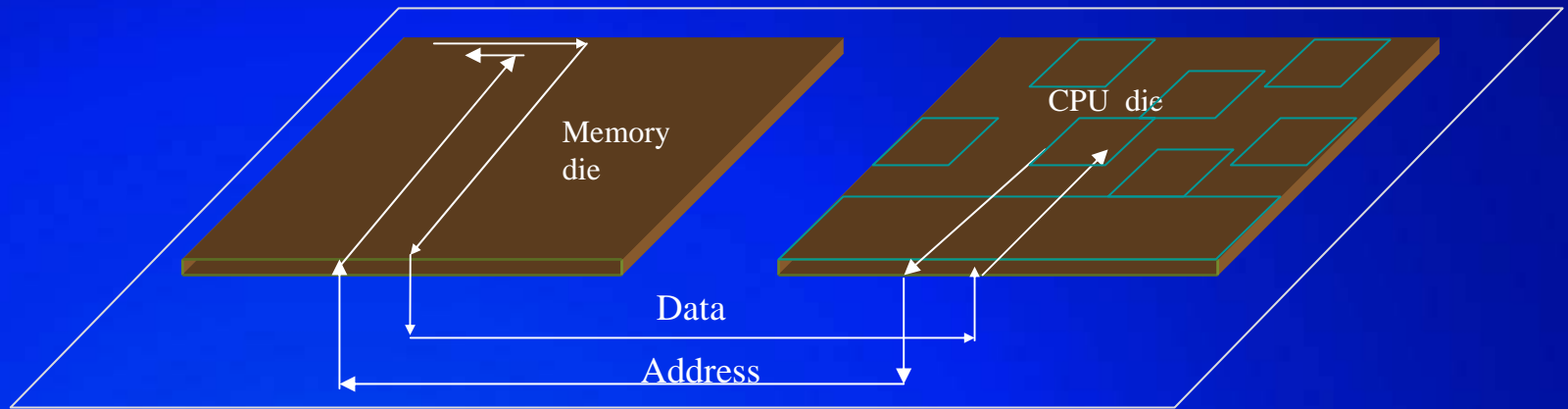
# *What about 3D for microprocessors?*



- Wiring is #2 limiter in chip level integration
  - 8 layers of metal
- Over half of performance loss is from wire delay
- Over half of power consumption is from wire capacitance
- Floorplan is a multivariate optimization exercise
  - Who wants to be next to whom?
  - Only 8 possible neighbors

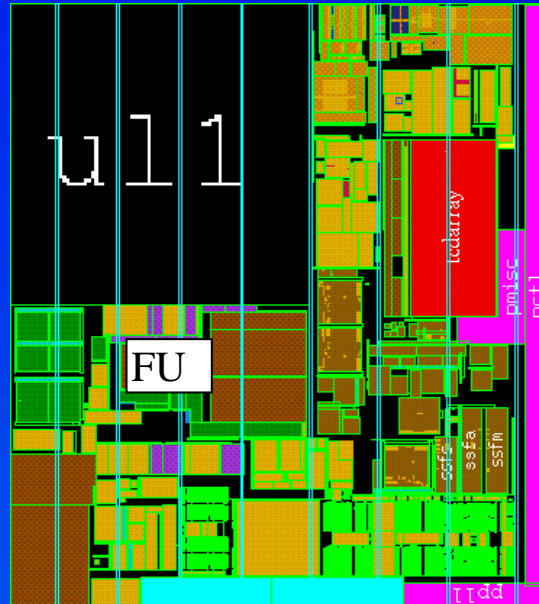
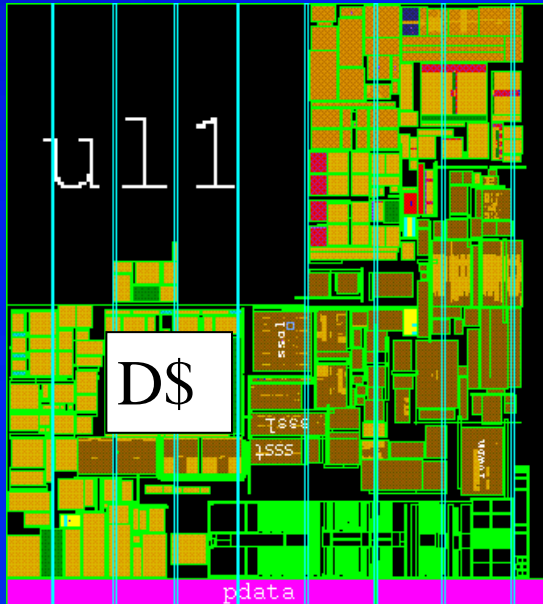
Re: Back et. al., ICCAD04

*Shorter Route, higher performance, lower power*





# Re-floorplan for 3D



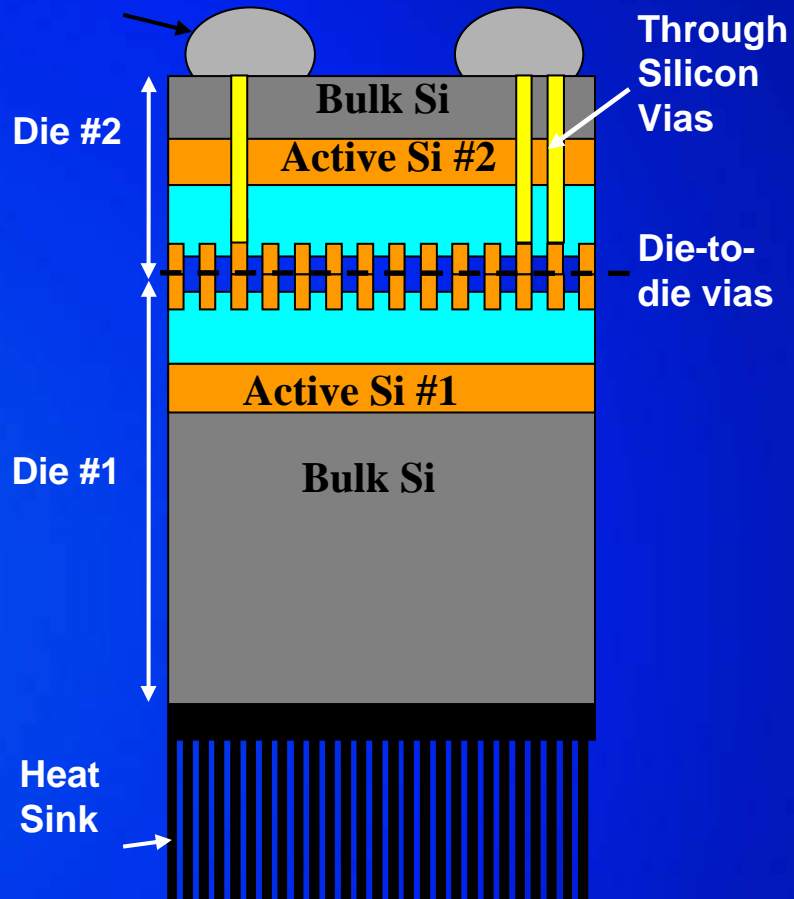
- Wires can be shortened to reduce wire delay and wireload
  - E.g. 50% less clock wires
- More flexibility for floorplanning
  - 2X more possible neighbor lots
- >15% Performance improvement
  - Pipe stage reduction
- 50% Less repeaters
- Caveats:
  - Avoid hot spot overlaps

Re: Back et. al., ICCAD04

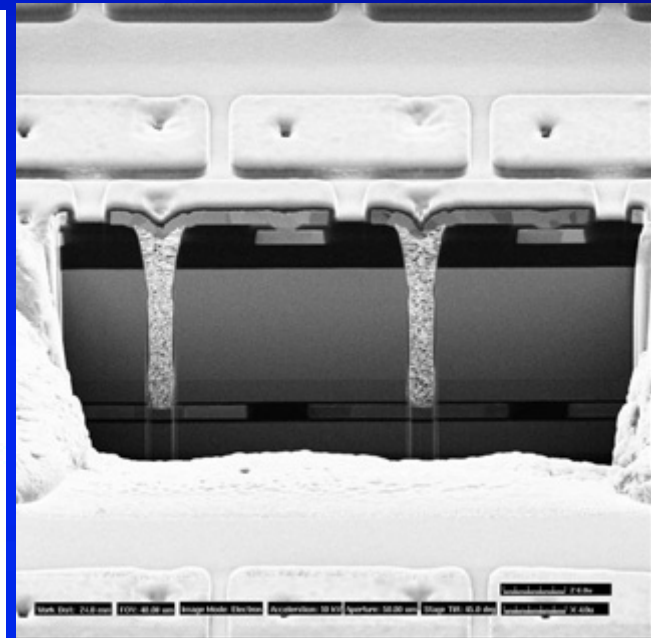
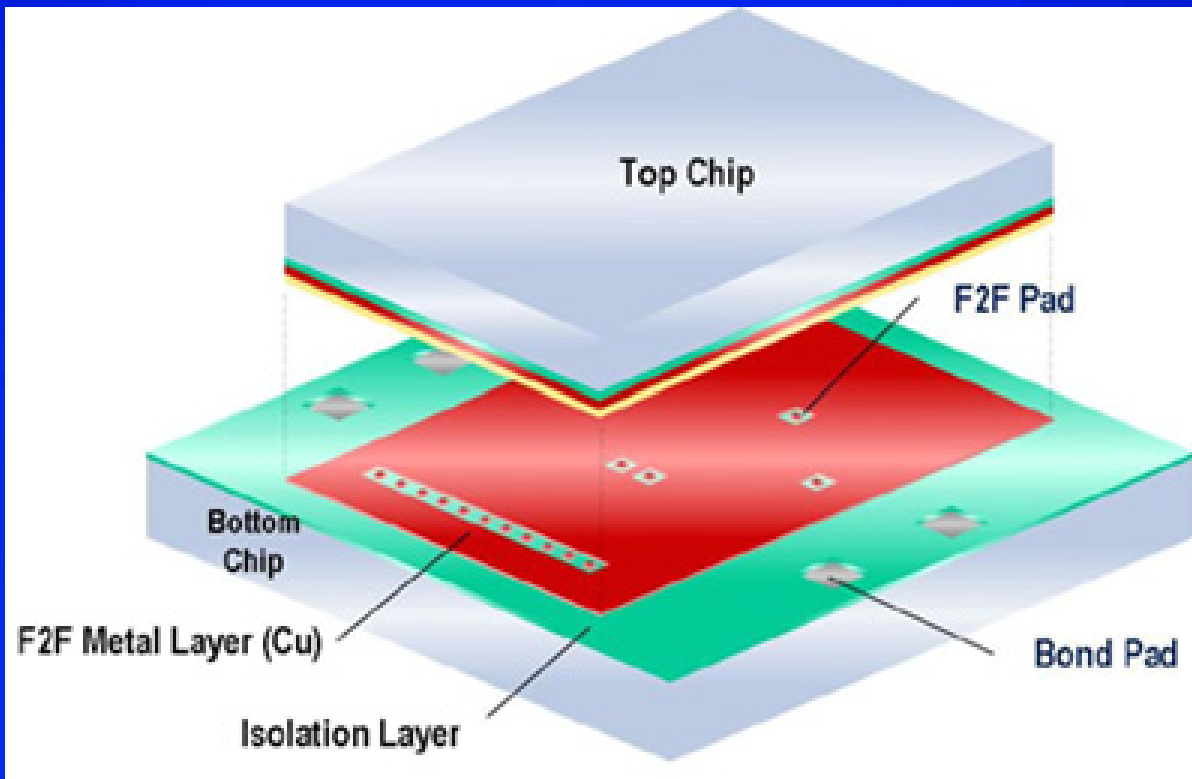
# 3D stack

- Face to face stacking
  - More die to die vias needed to facilitate the millions of connection between logic blocks

C4 I/O Bump



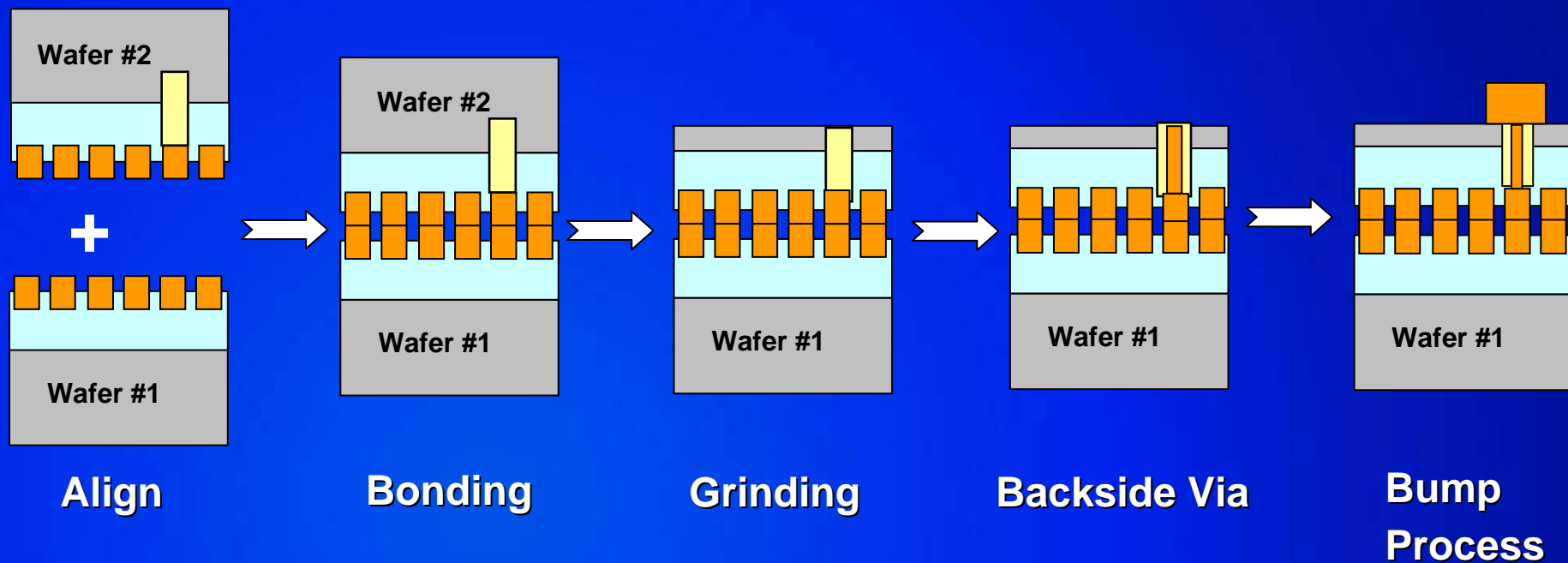
# Face-to-Face (F2F) Stacking Process



Thru Silicon Via

(re: Fraunhofer Gesellschaft, IZM, Munich)

# *Build process (F2F stack)*



Note buried via with wafer2

What does it mean to test?



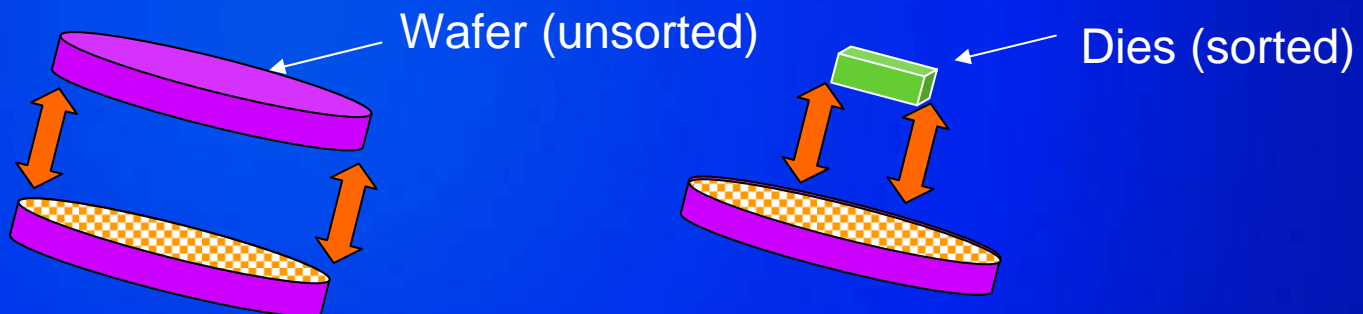
# *Die stack or wafer stack?*

- Wafer stack (blind assembly) would lower yield drastically

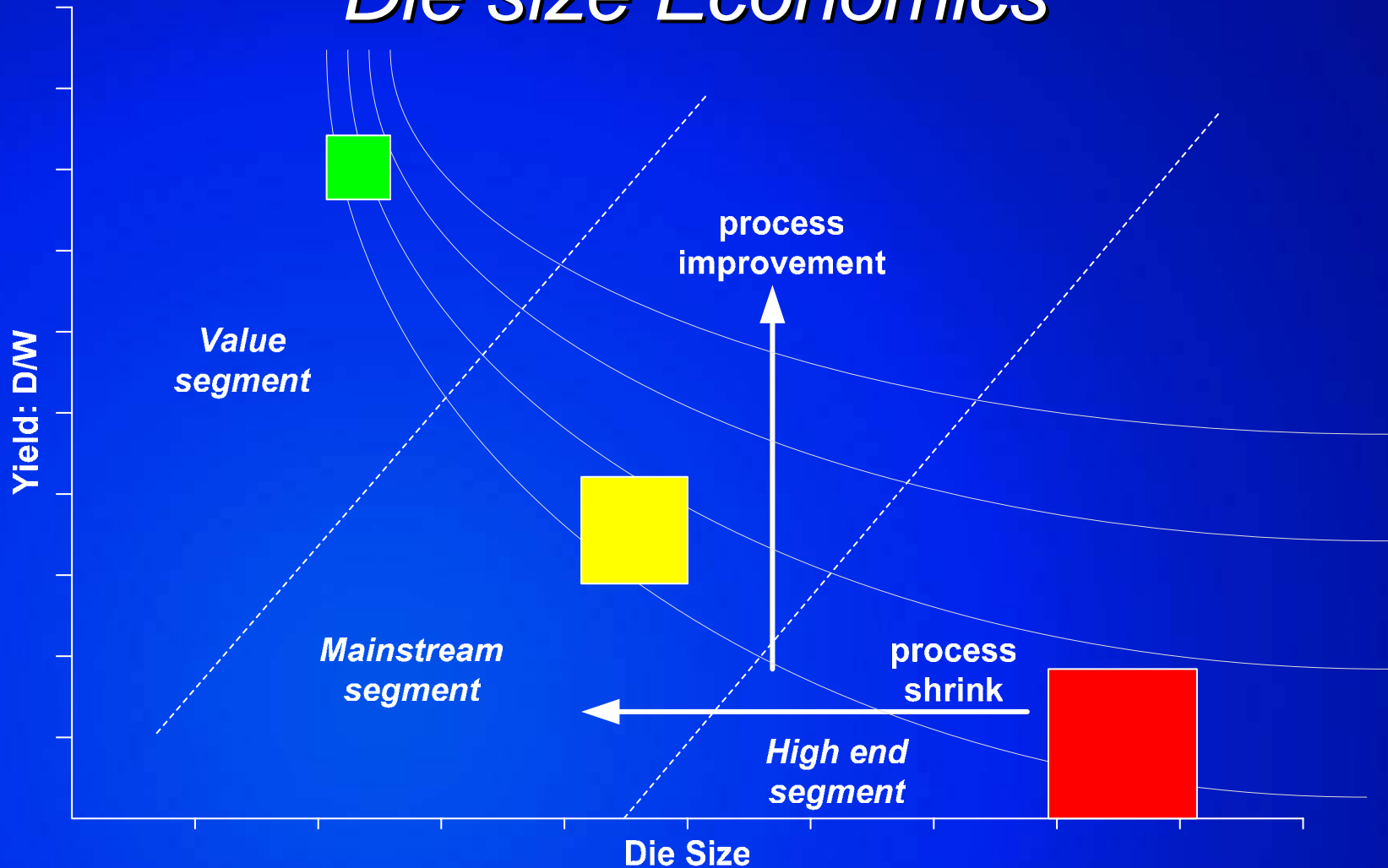
$$Y_{\text{stack}} = Y_{\text{top}} * Y_{\text{bottom}}$$

Note: this has not accounted for saving in pipestages or other wire/repeater reduction

- Die stacking allows better match of top and bottom die

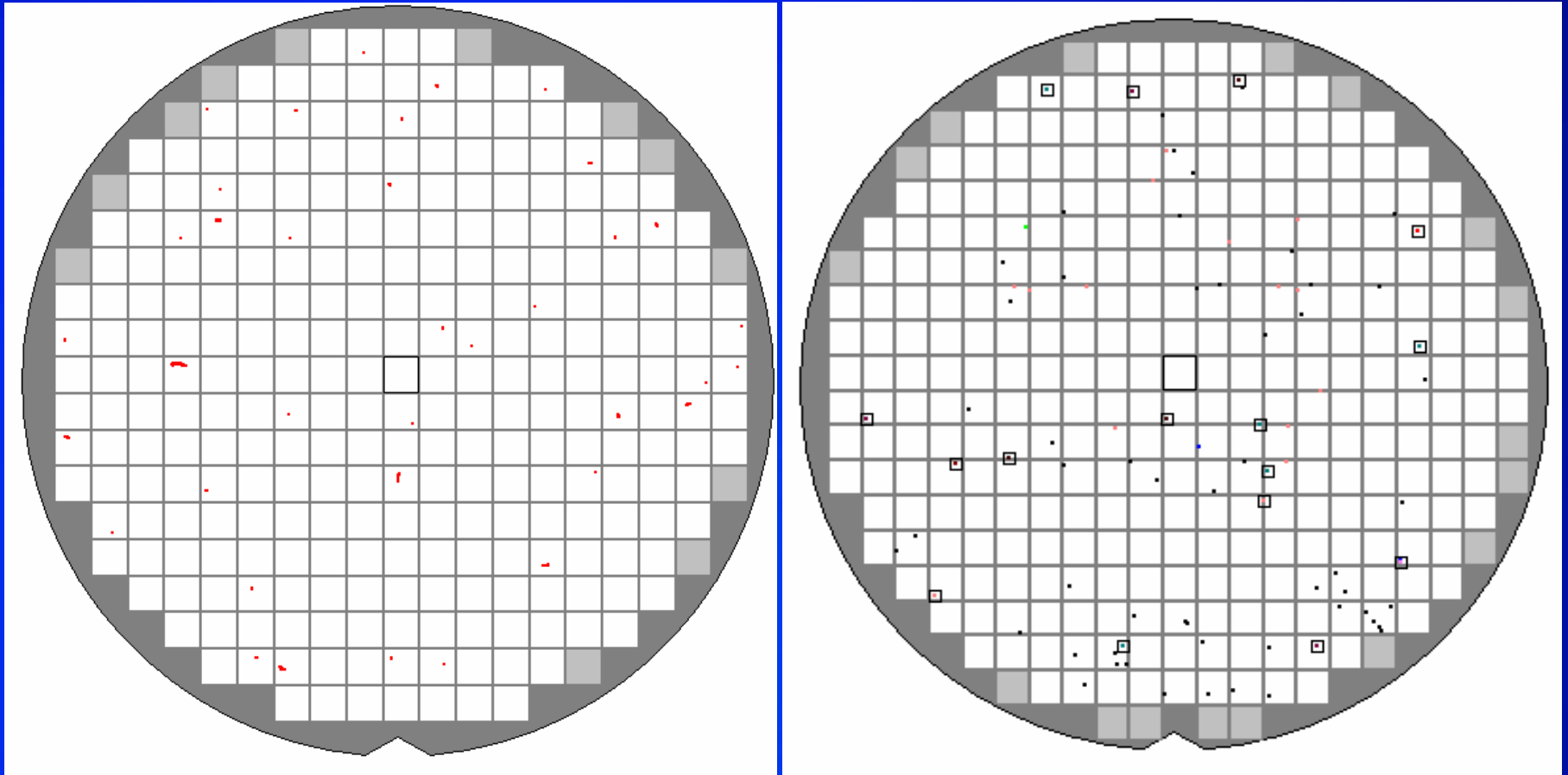


# Die size Economics



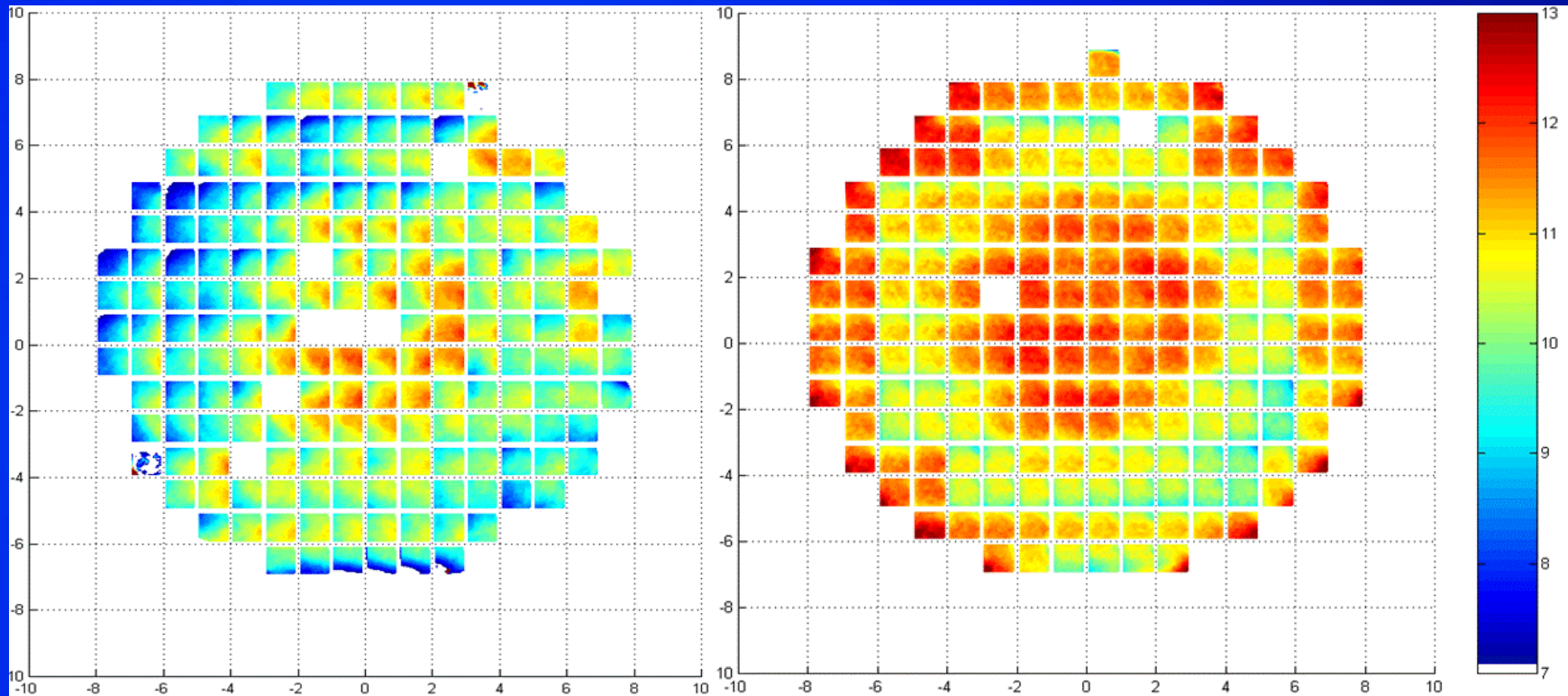
Will half the die size give you 2X yield?

*No 2 wafers have the same defect locations*



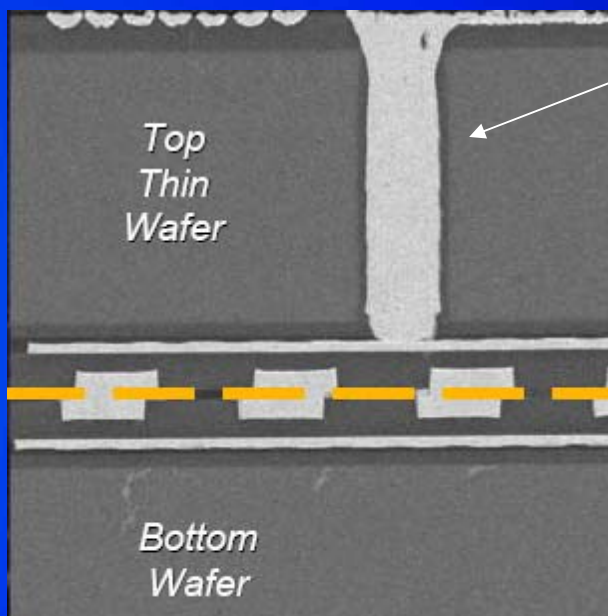
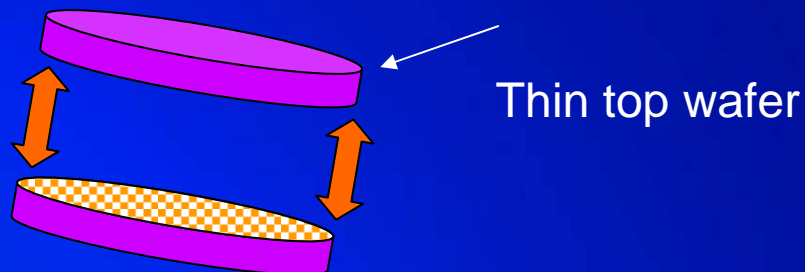
# *Process variation across wafers*

Fast top dies, slow bottom die? What is the result?



# Wafer thinning and stacking

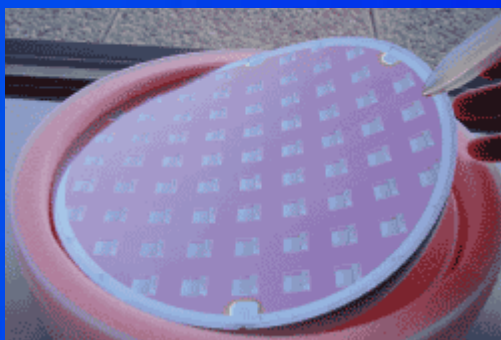
- To stack, you have to thin





# *Can you dare to probe thinned wafer?*

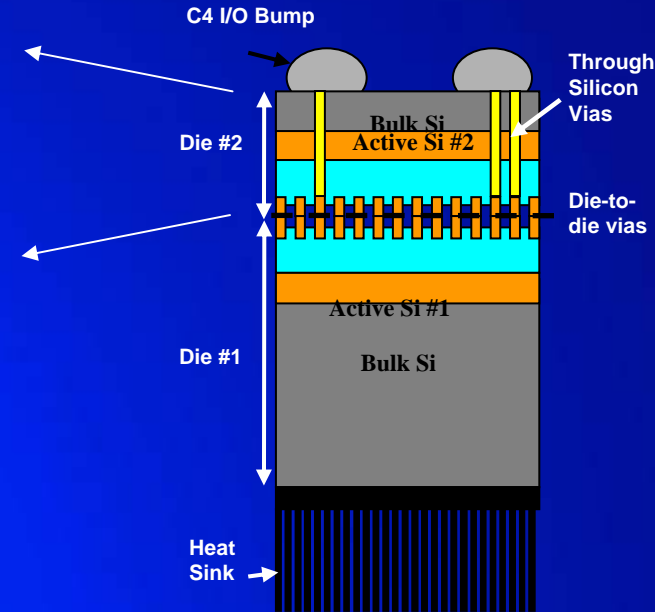
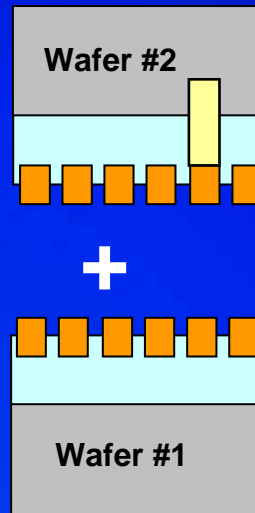
- 2gm of force per probe to ensure good enough electrical contact
  - Translate to 2,000 Kg/sqM force on each pad of a less than 100um silicon film



Source: IMEC

# *Why not probe unthinned wafer?*

- All connections to the bottom layers are in buried vias
  - This is where power, gnd and clocks come from
  - Bottom wafer only have tiny connections intended to connect to top wafer only
  - Same problem whether active layers are up or down



*The advantage of millions of connections quickly becomes **liability***

# Challenge?

- This is worse than **KGD**
  - ***Not a die yet !***
- Testing/Probing of partial circuits with very few connections from the top or bottom side
  - If a full blown infrastructures (thousands of probe pads) are built on top of the either wafer, the advantage will quickly lose appeal

***Manufacturing test  
can be another hurdle to 3D integration effort***

# *More challenges*

- Mixing and matching of top and bottom die require unprecedented process level information collection
  - On a monolithic die, there is no choice; not so when one can select (and match) them
- Thermal, loading at wafer/die level will not be the same when they are sandwiched together
  - Guardbands, margins all take their “taxes”



Can we solve all these problems?

We can't do it alone.

A close-up, blue-tinted photograph of two people's faces. The person on the left is in sharp focus, looking slightly off-camera. The person on the right is blurred, looking directly at the camera. The text "Let's create the future together." is overlaid in white, centered between the two faces.

Let's create the future together.

*Backup*

- Turning Chip Design on its Head, Wolfgang Gruber, Synopsys “Compiler” magazine
- 3D packaging issues for ultrasmall systems-in-a-cube, Eric Beyne et. al., *Solid State Technology* April, 2005
- 3D Processing Technology and its Impact on iA32 Microprocessors, Donald Nelson et. al., ICCAD2004
- [www.trusi.com](http://www.trusi.com)
- Through-wafer Via Etching, ANDREW A. CHAMBERS et. al., *Advanced Packaging* April, 2005
- Fabrication and Reliability Issues for Optical Components in Wafer Level Heterogeneous Hyper-Integration, Peter D Persans Sematech Workshop, Oct 25, 2004